

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Choi, et al.

Serial No.: 10/823,347

Filed:

April 12, 2004

For:

Gas Diffusion Shower Head Design For Large Area Plasma Enhanced **Chemical Vapor Deposition** 

MAIL STOP Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

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Group Art Unit: 1724

Examiner:

Unknown

## CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on November 9, 2005 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

November 9, 2005

Date

## STATUS INQUIRY

More than 18 months have passed since

the filing of this application on April 12, 2004.

the filing of . response on

No communication has been received from the Patent and Trademark Office indicating action on this application or response.

Kindly advise the undersigned of the present status of this application. stamped return-addressed envelope is provided.

Respectfully submitted,

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